ABSTRACT OF THE DISCLOSURE

CLEANING APPARATUS FOR SUBSTRATE

The invention provides A cleaning apparatus for a substrate which cleans a doughnut disk-like substrate which has a hole formed at the center, the cleaning apparatus comprising a jetting device for blowing a cleaning liquid against the substrate; and a chuck device arranged adjacent to the jetting device to support the substrate, wherein the chuck device includes a spindle chuck and a hydraulic rotating mechanism rotating the spindle chuck; and the hydraulic rotating mechanism includes a chassis member surrounding a rotary shaft of the spindle chuck and having therein a circulation channel for a driving fluid of the hydraulic rotating mechanism, a hydraulic turbine member provided in the circulation channel within the chassis member, and rotatably provided inside the chassis member to be connected to the rotary shaft of a spindle chuck, and a supply channel and a discharge channel for the driving fluid provided in the chassis member in order to supply the driving fluid to the circulation channel to rotationally drive the hydraulic turbine member.

Figure 1